

DIAGNOSTICS FOR INDUSTRIAL PROCESS CONTROL AND MEASUREMENT SYSTEMS

ABSTRACT OF THE DISCLOSURE

A field device includes diagnostic circuitry adapted to measure a characteristic related to a process control and measurement system. The measured characteristic is used to provide a diagnostic output indicative of a condition of the process control and measurement system. The measured characteristic can be provided to a diagnostic module that operates upon the measured characteristic to predict, or otherwise model, a condition of the process control and measurement system.